



Attorney Docket No. 59521 (48229)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: Hiroyuki Shimada

EXAMINER: Chen Kin Chan

U.S.S.N.: 10/678,994

GROUP ART UNIT: 1765

FILED: October 3, 2003

CONFIRMATION NO.: 8918

FOR: METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE
INCLUDING ETCHING A CONDUCTIVE LAYER BY USING A GAS
INCLUDING SiCl_4 and NF_3

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By


Nicole M. McKinnon

.....
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Sir:

AMENDMENT UNDER 37 C.F.R. § 1.111

In response to the Office Action dated June 20, 2005, Applicant submits the following amendment.

Amendment Under 37 C.F.R. § 1.111
U.S.S.N.: 10/678,994
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IN THE TITLE:

Please change the title to the following title:

METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE INCLUDING
ETCHING A CONDUCTIVE LAYER BY USING A GAS INCLUDING SiCl_4 and
 NF_3